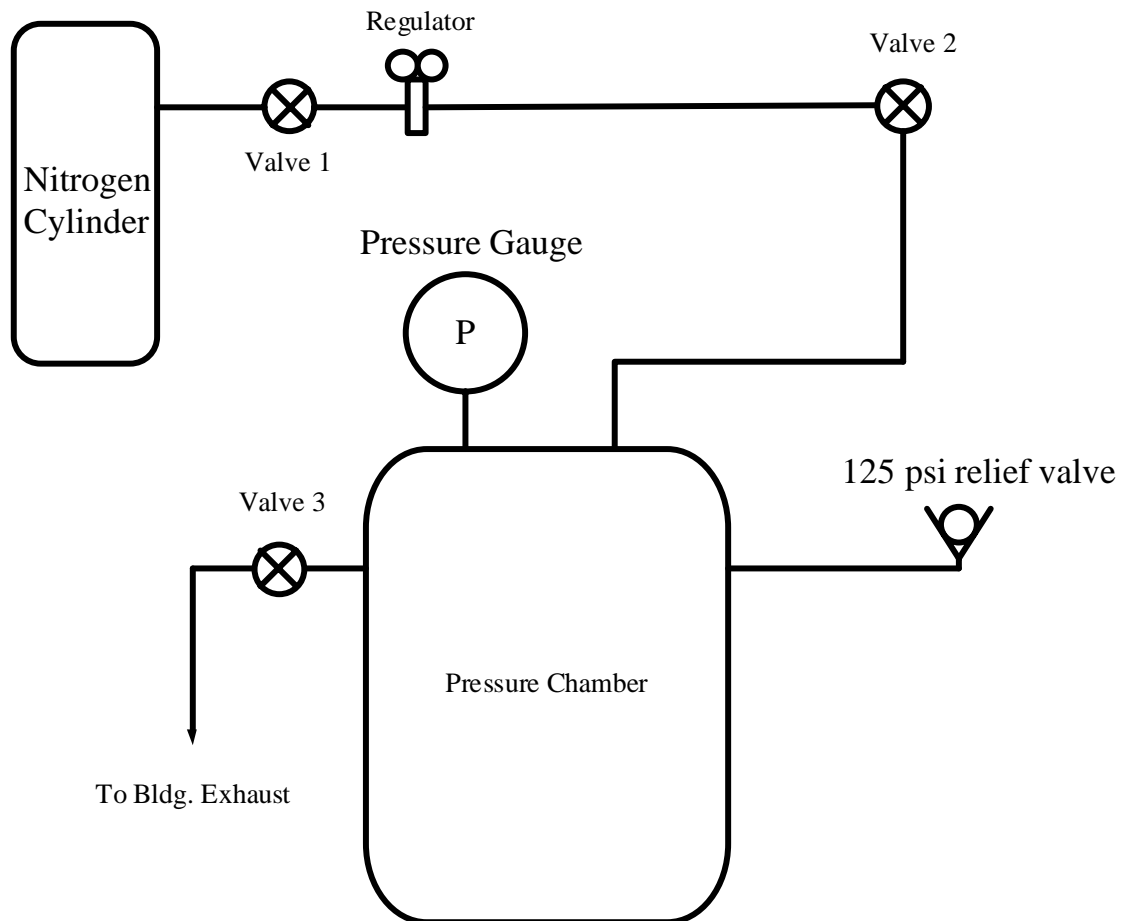


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Gas System and Operating Procedure for Pressure Chamber.

I have constructed a simple gas system for use in pressurizing the pixel carrier assemblies after using the film adhesive. This is to aid in the adhesion by significantly shrinking the bubbles generated in the application of this adhesive. The gas system schematic and operating procedure are given below.

The nitrogen pressurization system consists of the components shown below:



Operating Procedure

All valves are to be closed at the beginning of the procedure. The relief valve is set to 125 psig. Please do not pressurize the chamber to any pressure higher than 100 psig.

To Pressurize the Chamber.

1. Place the carrier into the chamber and seal the pressure door.
2. Open Valve 1
3. Open valve 2
4. Adjust the regulator to the desired pressure (~90 psig).
5. When the pressure in the chamber reaches 90 psig as measured on the pressure gauge, close valve 2 and valve 1. Adjust the regulator back to 0 psig pressure (off)
6. Let the carrier in the pressurized system sit at pressure for ~12 hours.
7. Open valve 3 to exhaust the nitrogen into the building exhaust.
8. Remove carrier.
9. The process is now complete.